

Title (en)

Ion source in which a UV/VUV light source is used for ionization

Title (de)

Ionenquelle, bei der UV/VUV-Licht zur Ionisation verwendet wird

Title (fr)

Source d' ions dans laquelle une source de lumière UV/VUV est utilisée pour l' ionisation

Publication

**EP 1220285 A3 20050316 (DE)**

Application

**EP 01120299 A 20010824**

Priority

DE 10044655 A 20000909

Abstract (en)

[origin: DE10044655A1] The ion source has an ionisation chamber and a UV/VUV-excimer light source for generating ions by directing light into a sample gas. The light source is provided by a deuterium lamp, a micro hollow cathode lamp, a micro point lamp, a DC discharge lamp, a barrier discharge lamp, or an electron beam UV/VUV lamp, with an electron gun (1), a membrane (3) between the electron gun and a gas space (9) containing a rare earth gas or gas mixture and optical elements (11,12) for imaging the light emission volume into the ionisation space (14).

IPC 1-7

**H01J 49/16; H01J 27/24**

IPC 8 full level

**H01J 49/16** (2006.01); **H01J 49/40** (2006.01)

CPC (source: EP)

**H01J 49/162** (2013.01)

Citation (search report)

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CN111929354A; CN107014892A

Designated contracting state (EPC)

AT BE CH CY DE DK ES FI FR GB GR IE IT LI LU MC NL PT SE TR

DOCDB simple family (publication)

**DE 10044655 A1 20020404**; EP 1220285 A2 20020703; EP 1220285 A3 20050316; EP 1220285 B1 20140820

DOCDB simple family (application)

**DE 10044655 A 20000909**; EP 01120299 A 20010824